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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
: Examiner: Bret P. Chen
TAKAHARU KONDO, ET AL.)
: Group Art Unit: 1762
Application No.: 09/865,549)
: Filed: May 29, 2001)
: For: METHOD OF FORMING)
SILICON-BASED THIN FILM,)
SILICON-BASED THIN FILM)
AND PHOTOVOLTAIC ELEMENT)

August 28, 2003

Mail-Stop No-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

a) Introductory Comments:

In response to the outstanding Office Action dated May 28, 2003, kindly amend the subject application as follows:

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on

August 28, 2003
(Date of Deposit)

PETER SAXON (24947)

(Name of Attorney for Applicant)

Peter Saxon

Signature

August 28, 2003

Date of Signature